

Dry Etch

Recipes run in Equipments

Abhijit Roy

Sci./Engr. - 'SD'

CL00102

VFD, Dry Etch

31-Mar-2021

Background

- The shared raw data contains the recipes used for running lots in equipment(s)/chamber(s) with datetime.

Objective

- List down the unique recipes run in respective equipment(s)/chamber(s).
- Show the frequency of each recipe run in respective equipment(s)/chamber(s).

ASBE1

Recipes

```
['#D',
': Recipe # D',
'TS18SL_STRIP',
'Recipe # D.',
'Recipe: Recipe # 2',
'Recipe: Recipe # D',
'F',
'ipe # B( if in ASBE1); Recipe:TS18SLSTRIP(if in ASP Chamber of CLREML1).',
'Recipe#7(300sec) in ASFE1,Recipe:TS18SLStrip in ASP Chamber',
'Recipe # 4',
'2',
'See Remarks for recipes.',
': Recipe # 2',
'Recipe # 3',
'V2PreDUVASH',
'# 2',
'#1',
'B',
'Recipe#1',
'test',
'TS18SLSTRIP',
'#3',
'# D',
'D',
'# 3',
'#6',
'3',
'# D.',
'#d',
'Recipe # D',
'See Remark',
'Recipe#6',
'#2',
'TS18SL_STRIP',
'Recipe 1',
'Recipe # 2',
'TS18SLSTRIP-REML1']
```

Frequency

ASFE1

Recipes

```
[ '2,5,and 1',
'#D',
': Recipe # D',
'NOTE: After ASH, arrange wafers in corresponding slots in the wafer sorter.  Recipe: Recipe # D',
'B D',
'Recipe # D.',
'Recipe: Recipe # 2',
'Recipe: Recipe # D',
'1902',
'F',
'CID_ASHING-NFM--Post',
'Recipe # 4',
'Recipe:2',
'2',
'Recipe F',
'Recipe# 2',
'Recipe D',
': Recipe # 2',
'RecipeD',
'ASHER1',
'Recipe # 3',
'Z-SIPMGC1',
'# 2',
'Recipe 2',
'Recipe 3',
'60 sec',
'6',
'ASH',
'TS18SLSTRIP',
'#3',
'# 3',
'D',
'# D',
'#6',
'Recipe2',
'pre duv ash',
'Recipe: Recipe # 3',
'3',
'# D.',
'#d',
'Recipe 2',
'Recipe 3',
'Recipe 3',
'Recipe D',
'sorter.  Recipe: Recipe # D',
'60 s',
'NO Run',
'RAA FI"',
': #2',
'Recipe # D',
'e# 2',
': Recipe # 3',
'ASHER1--CNS Ash',
'#2',
'2 and 1',
'ecipe: #2',
'D B',
'Recipe 2',
'Recipe#2',
'Recipe-2',
'recipe D',
'Recipe: #2',
'e#2',
'Recipe D',
'd',
'Recipe # 2',
'Post GC Ash']
```


Frequency

REML1

Recipes

Frequency

REOX1

Recipes

Frequency

REPL1

Recipes

Frequency

RESP1

Recipes

Frequency

THANKS

